

Resource Summary Report

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FEI: Helios NanoLab 1200AT DualBeam for Semiconductors

RRID:SCR_019886

Type: Tool

Proper Citation

FEI: Helios NanoLab 1200AT DualBeam for Semiconductors (RRID:SCR_019886)

Resource Information

URL: https://raw.githubusercontent.com/SciCrunch/RRID-Instruments/refs/heads/main/PDF/SCR_019886.pdf

Proper Citation: FEI: Helios NanoLab 1200AT DualBeam for Semiconductors (RRID:SCR_019886)

Description: Wafer analysis system that can create site-specific transmission electron microscope (TEM) samples thin enough to capture a single transistor at the 10nm node, from wafers up to 300mm in diameter.

Resource Type: instrument resource

Keywords: FEI, DualBeam Microscope, Instrument Equipment, USEDit,

Availability: Commercially available

Specification URL: https://raw.githubusercontent.com/SciCrunch/RRID-Instruments/refs/heads/main/PDF/SCR_019886.pdf

Resource Name: FEI: Helios NanoLab 1200AT DualBeam for Semiconductors

Resource ID: SCR_019886

Alternate IDs: Model_Number_NanoLab 1200AT

Old URLs: <https://www.fei.com/products/dualbeam/helios-nanolab-1200at-for-semiconductors/>

Record Creation Time: 20220129T080347+0000

Record Last Update: 20260815T182628+0000

Ratings and Alerts

No rating or validation information has been found for FEI: Helios NanoLab 1200AT DualBeam for Semiconductors.

No alerts have been found for FEI: Helios NanoLab 1200AT DualBeam for Semiconductors.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.